

## **GUJARAT TECHNOLOGICAL UNIVERSITY**

**BE- SEMESTER-VII (NEW) EXAMINATION – WINTER 2020** 

| Subject Code:2170311 | Date:30/01/2021 |
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**Subject Name:Biomedical Microsystems** 

| Time:10:30 AM TO 12:30 PM | Total Marks: 56 |
|---------------------------|-----------------|
|---------------------------|-----------------|

## **Instructions:**

- 1. Attempt any FOUR questions out of EIGHT questions.
- 2. Make suitable assumptions wherever necessary.
- 3. Figures to the right indicate full marks.

|              |              |                                                                                                                         | MARKS      |
|--------------|--------------|-------------------------------------------------------------------------------------------------------------------------|------------|
| Q.1          | (a)          | What are Miller indices?                                                                                                | 03         |
|              | <b>(b)</b>   | Explain Sputtering in detail.                                                                                           | 04         |
|              | <b>(c)</b>   | Explain PVD techniques used in MEMS technology.                                                                         | 07         |
| Q.2          | (a)          | Discuss various alternate materials used for manufacturing of MEMS.                                                     | 03         |
|              | <b>(b)</b>   | Explain Plasma etching with neat diagram                                                                                | 04         |
|              | <b>(c)</b>   | Explain CVD technique used in manufacturing of MEMS.                                                                    | 07         |
| Q.3          | (a)          | Explain the effect of residual stress on MEMS device. Discuss the                                                       | 03         |
|              | <b>(3.</b> ) | equation which is used to find residual stress.                                                                         | 0.4        |
|              | <b>(b)</b>   | Explain sacrificial surface micromachining. Mention the different sacrificial used with different structural materials. | 04         |
|              | (c)          | Explain Wet etching with neat diagram.                                                                                  | 07         |
| Q.4          | (a)          | Write and explain various CVD reactions.                                                                                | 03         |
|              | <b>(b)</b>   | Explain manufacturing of Silicon On Insulator (SOI) substrate with                                                      | 04         |
|              |              | neat diagram.                                                                                                           |            |
|              | (c)          | Explain LIGA fabrication process.                                                                                       | 07         |
| Q.5          | (a)          | Explain process of annealing in MEMS                                                                                    | 03         |
|              | <b>(b)</b>   | Explain concept of electron tunneling.                                                                                  | 04         |
|              | <b>(c)</b>   | Explain Lift off process with neat diagram.                                                                             | 07         |
|              |              |                                                                                                                         |            |
| Q.6          | (a)          | Explain concept of diffusion used in material doping. Give equation which governs the diffusion process.                | 03         |
|              | <b>(b)</b>   | With neat diagram explain the process of Implantation used in doping                                                    | 04         |
|              |              | process.                                                                                                                |            |
|              | (c)          | Explain Diagnostic and Therapeutic Applications of Metal Nano shells.                                                   | 07         |
| 0.7          | (a)          | Explain current challenges in drug delivery and the remedies.                                                           | 03         |
| <b>Q•</b> ′′ | (b)          | Write short note on Biosensors arrays and Implantable devices.                                                          | 04         |
|              | (c)          | Explain Quantum dots usefulness as optical probes. Give one example.                                                    | 07         |
| Q.8          | (a)          | Discuss materials which are used in drug delivery.                                                                      | 03         |
| <b>Q.</b> 0  | (a)<br>(b)   | Give classification of physical sensors, Integrated, Intelligent or Smart                                               | 03         |
|              |              | sensors                                                                                                                 | <b>U-T</b> |
|              | (c)          | With neat diagram explain any one MEMS actuator design.                                                                 | 07         |

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